IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Zongtao GE

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Art Unit:

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Filed: January 22, 2001

Examiner: TO BE ASSIGNED

For: Phase Shift Fringe Analysis Method and Apparatus Using th

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U.S. PATENT DOCUMENTS					
Examiner Initials*	U.S. Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY		

FOREIGN PATENT DOCUMENTS							
Examiner Initials *	Foreign Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	7**			

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS					
Examiners Initials*	Include Author (CAPITAL-LETTERS), title of article, book, magazine, etc. date, page(s), volume-issue number(s), publisher, city and/or country where published	т**			
ML	MITSUO TAKEDA, "Subfringe Interferometry Fundamentals", Kogaku, February 1984, pp. 55-65, Vol. 13, No. 1, Japan				
Mer	KATHERINE CREATH, "Phase-Measurement Interferometry Techniques", Progress in Optics, E. Wolf, Editor, 1988, pp. 349-393, Vol. XXVI, Elsevier Science Publishers B.V., New York, U.S.A.				

	Examiner Signature		Date Considered	April	21,2004	
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^{*}Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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